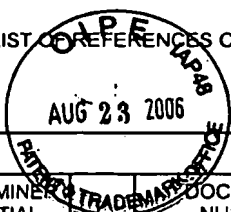


Form PTO 1449 (Modified)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO. 268668US26PCT		SERIAL NO. 10/529,191	
LIST OF REFERENCES CITED BY APPLICANT 				APPLICANT Takahiro HORIGUCHI, et al.			
				FILING DATE March 24, 2005		GROUP 2812	
U.S. PATENT DOCUMENTS							
EXAMINER'S INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE	
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						
	AM						
	AN						
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION YES NO		
/RD/	AO	3-77315	04/02/1991	Japan (with English Abstract)		X	
/RD/	AP	10-270436	10/09/1998	Japan (with English Abstract)		X	
	AQ						
	AR						
	AS						
	AT						
	AU						
	AV						
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)							
	AW						
	AX						
	AY						
	AZ					<input type="checkbox"/> Additional References sheet(s) attached	
Examiner /Rakesh Dhingra/				Date Considered 06/16/2007			
*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							

Form PTO 1449
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PATENT AND TRADEMARK OFFICEATTY DOCKET NO.
268668US26PCTSERIAL NO.
10/529,191

LIST OF REFERENCES CITED BY APPLICANT

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Takahiro HORIGUCHI, et al.FILING DATE
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GROUP

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/RD/	AA	5,903,711	05/11/99	OKASE, Wataru			
/RD/	AB	5,904,872	05/18/99	ARAMI, Junichi et al.			
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	AD						
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	AL						
	AM						
	AN						

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION	
					YES	NO
/RD/	AO	09-30893	02/04/97	JP(with English abstract)		NO
/RD/	AP	05-047687	02/26/93	JP(with English abstract)		NO
	AQ					
	AR					
	AS					
	AT					
	AU					
	AV					

OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)

/RD/	AW	Z. H. LU: "SiO ₂ film thickness metrology by x-ray photoelectron spectroscopy", Appl. Phys. Lett., Vol. 71, No. 19, November 10, 1997.				
	AX					
	AY					
	AZ					<input type="checkbox"/> Additional References sheet(s) attached

Examiner

/Rakesh Dhingra/

Date Considered

06/16/2007

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